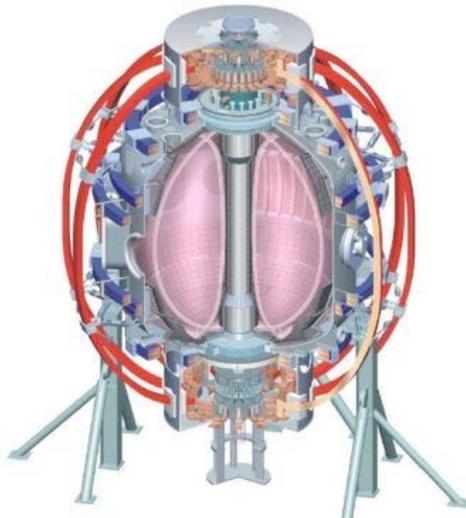


Absorber arc mitigation during CHI on NSTX

**D. Mueller, M.G. Bell, A.L. Roquemore,
R. Raman, B.A. Nelson, T.R. Jarboe and
the NSTX Research Team**

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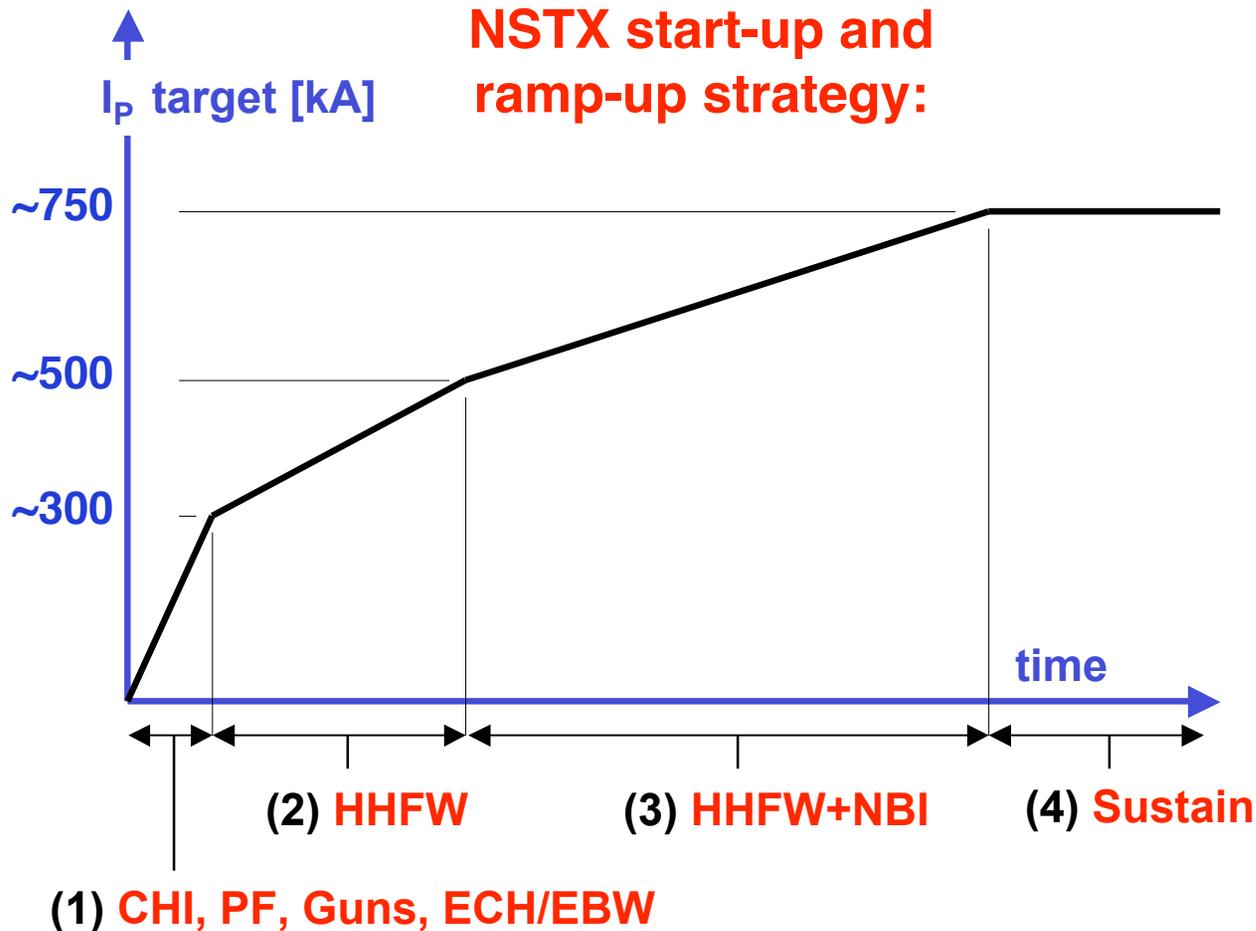
**DPP09 Meeting
Atlanta, GA
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Supported by U.S. D.O.E. Contract #
DE-AC02-09-CH11466, DE-FG03-96ER54361, and DE-AC52-07NA27344.

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Three Phases for Non-inductive Start-up and Ramp-up in NSTX



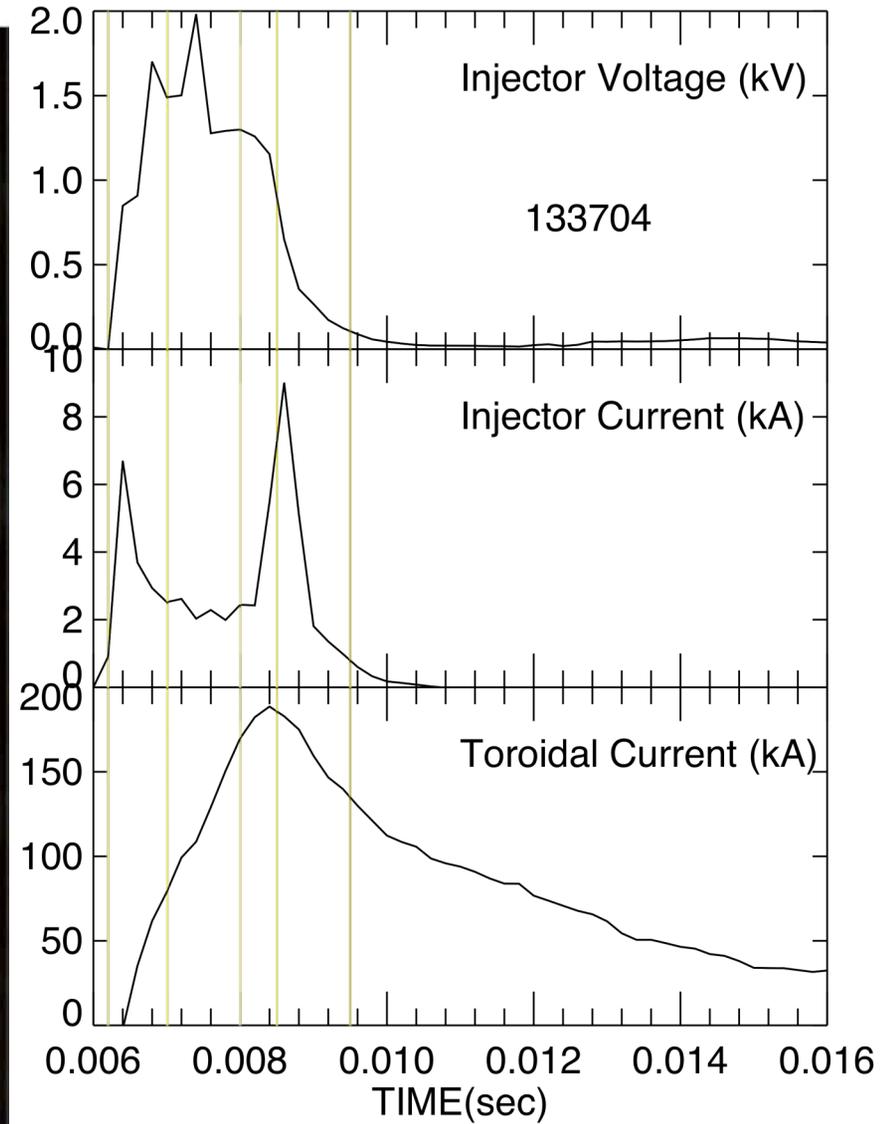
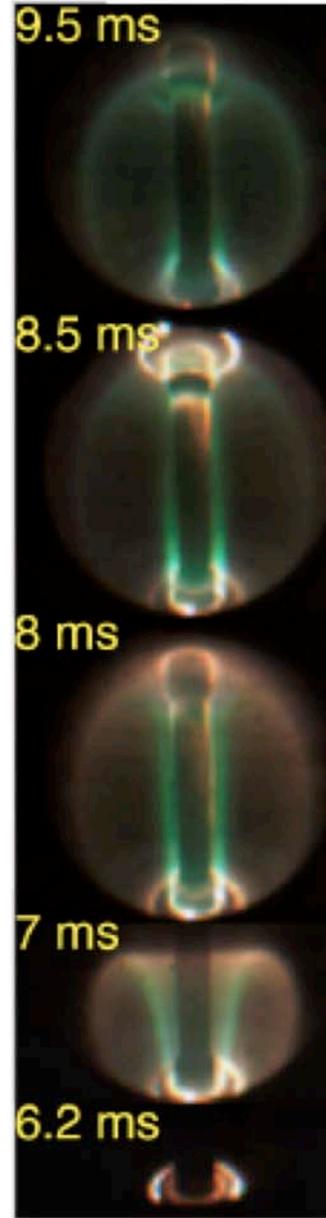
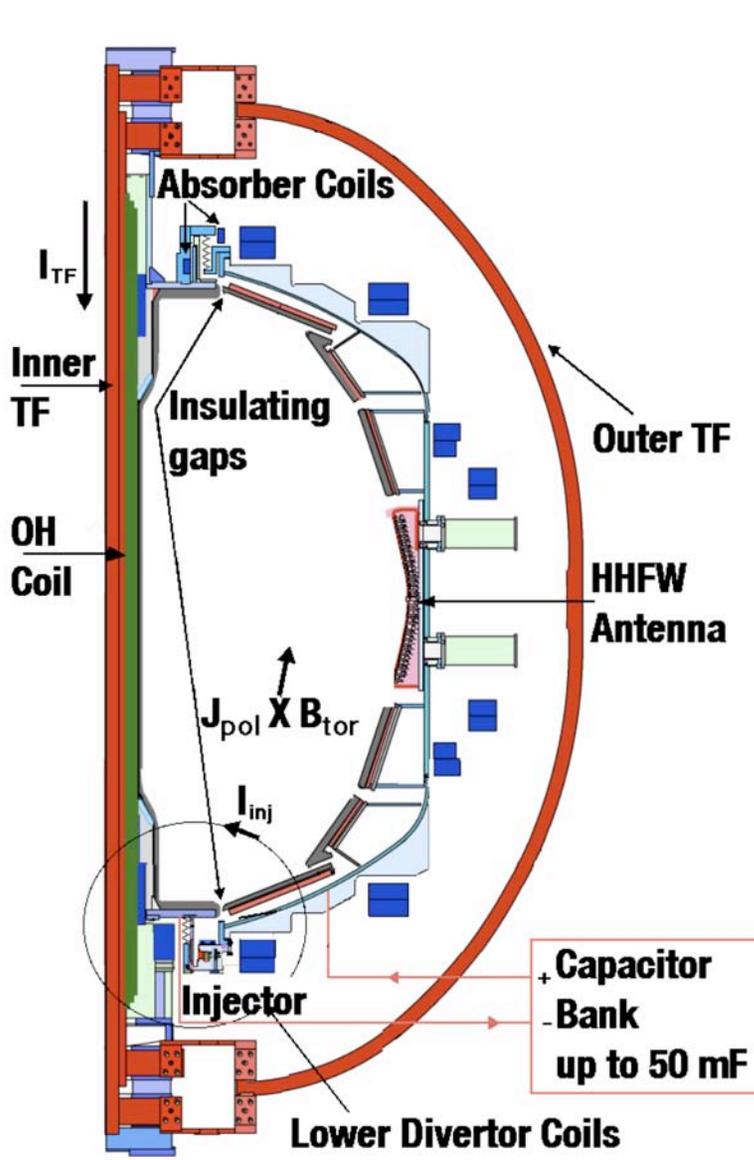
Start-up/ramp-up requirements:

- (1→2) I_p , T_e must be high enough for HHFW to be absorbed
- (2) High P_{RF} , τ_E must be achieved for I_p overdrive with BS and HHFW current drive
- (2→3) High I_p needed to absorb NBI, high P_{HEAT} , τ_E , β_p needed for current overdrive
- (3→4) Ramp-up plasma must be consistent with sustained high- f_{NI} scenario

Use OH as needed to simulate I_p ramp-up

Focus on transition from CHI start-up to ohmic ramp-up

Transient CHI: Axisymmetric reconnection leads to formation of closed flux surfaces



• Peak $T_e \sim 20 \text{ eV}$

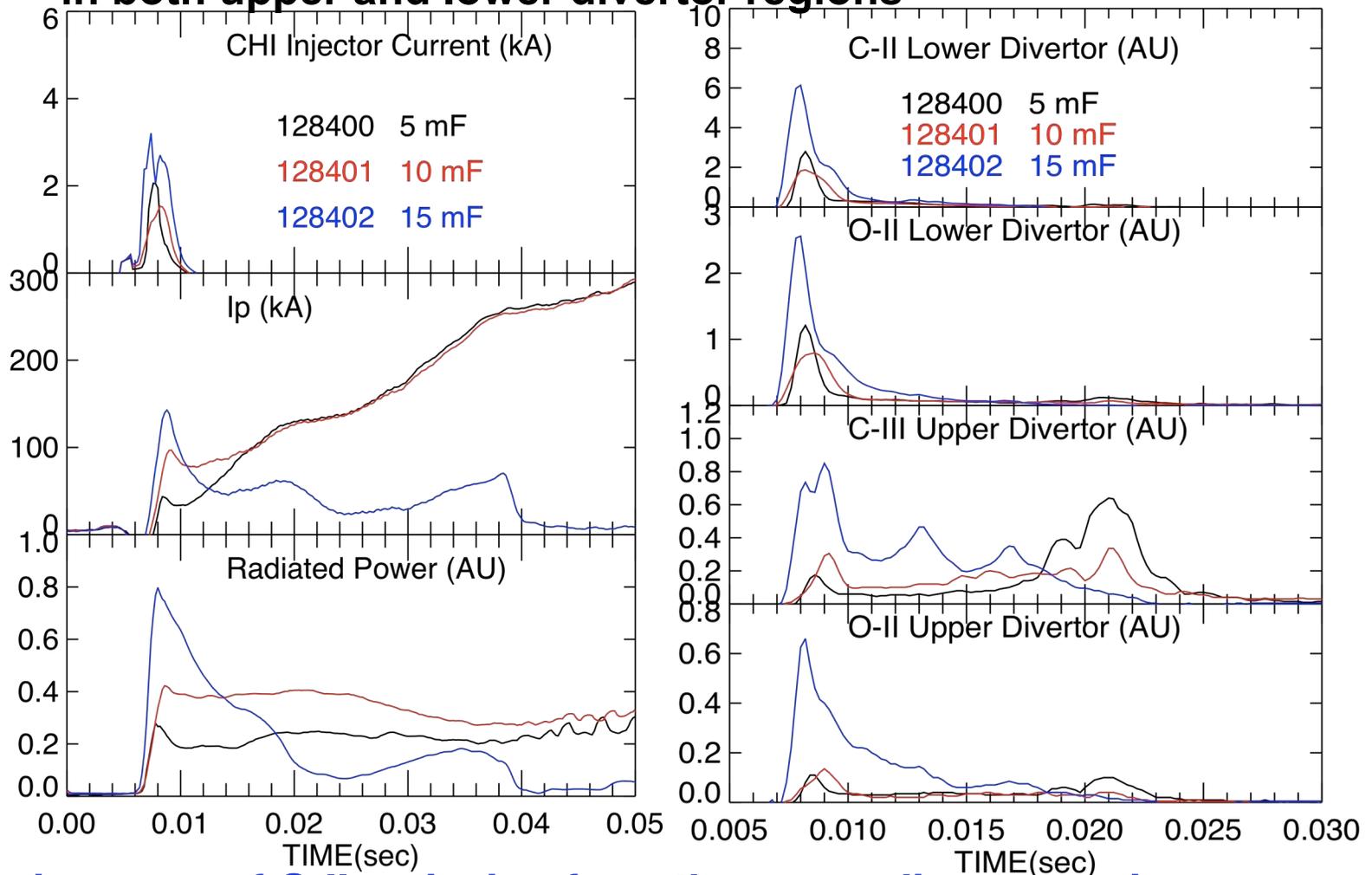
Three successive CHI discharges using an ohmic ramp exhibit increased radiated power with increased energy

Low-Z impurity radiation increases with increased injection energy
in both upper and lower divertor regions

128400
5mF (7.6kJ)
Peak T_e (8,12 ms)
~10eV

128401
10mF (15.3kJ)
Peak T_e (8,12 ms)
~20eV

129402
15mF (22.8kJ)
Peak T_e (8,12 ms)
<10eV

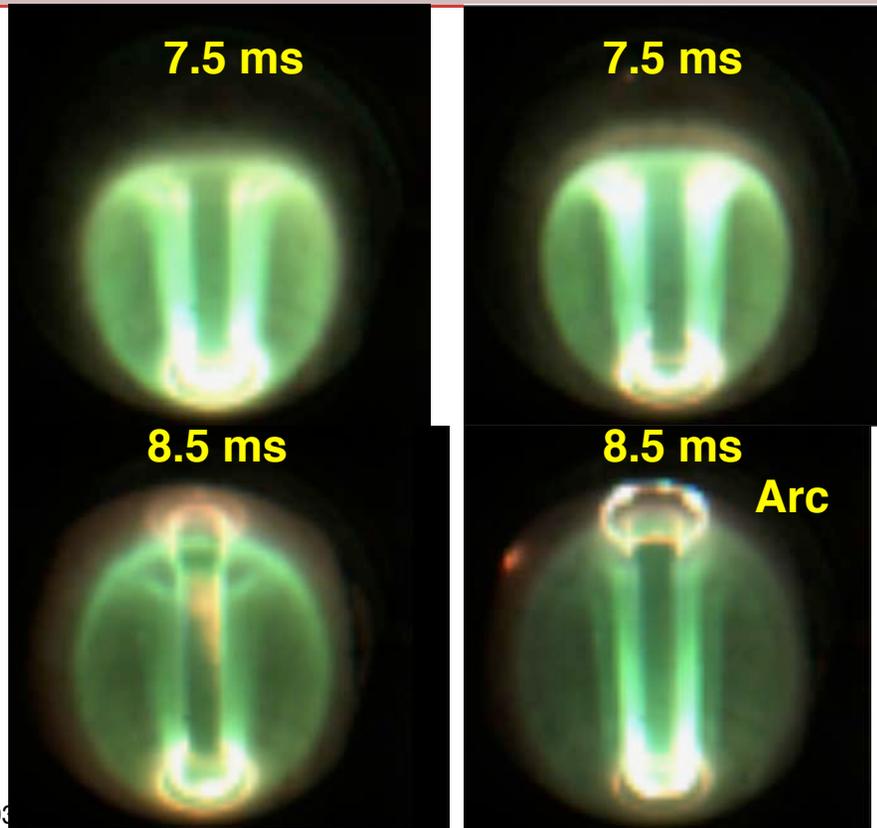
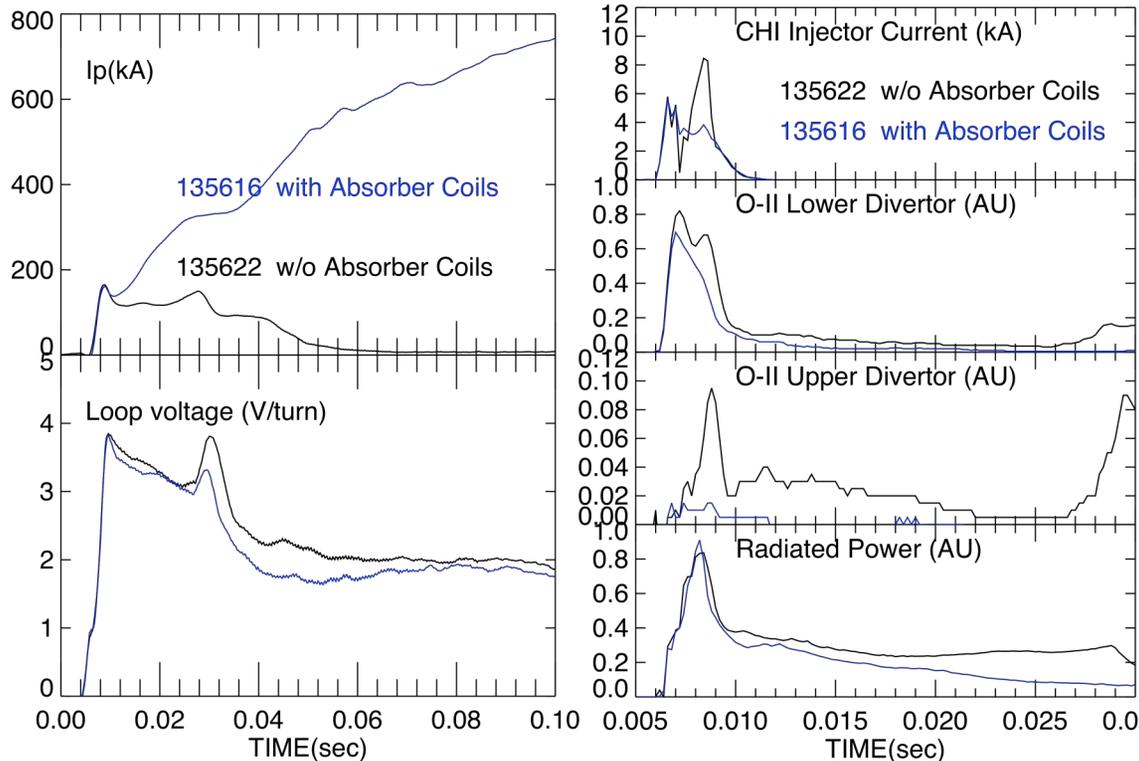


- Note Dramatic increase of O-II emission from the upper divertor region
- Absorber arcs are major cause of this emission and lead to low T_e

Strategies to reduce oxygen or mitigate absorber arcs

- Coat surfaces with Lithium to reduce Oxygen
 - Best results with LITER, little experience with Li powder
- Condition divertor surfaces with rectifiers with 400 ms, 5 kA CHI discharges
 - Best results followed a day of this conditioning
- Increase impedance of absorber (upper) gap
 - Use absorber coils to reduce poloidal field at absorber
 - Did not achieve better result, dynamic response is too slow
- Use absorber coils to provide buffer flux to prevent plasma from reaching absorber during CHI
 - Clearly reduced incidence of absorber arcs

Radial field from absorber coils prevents plasma from reaching absorber gap during CHI

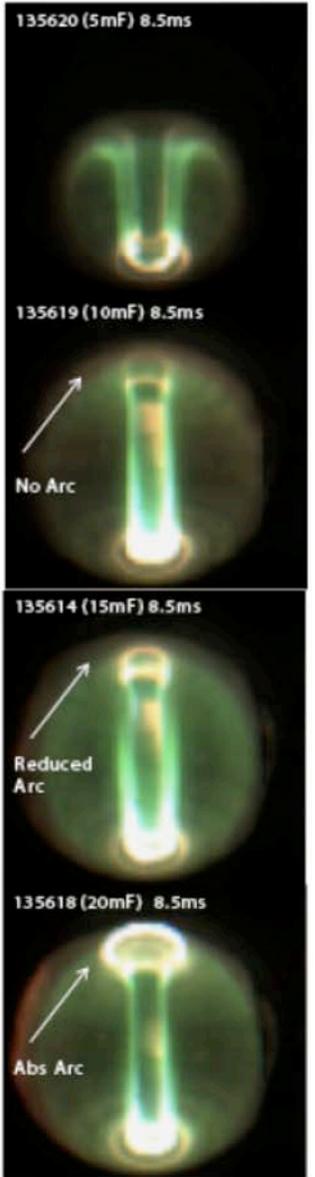
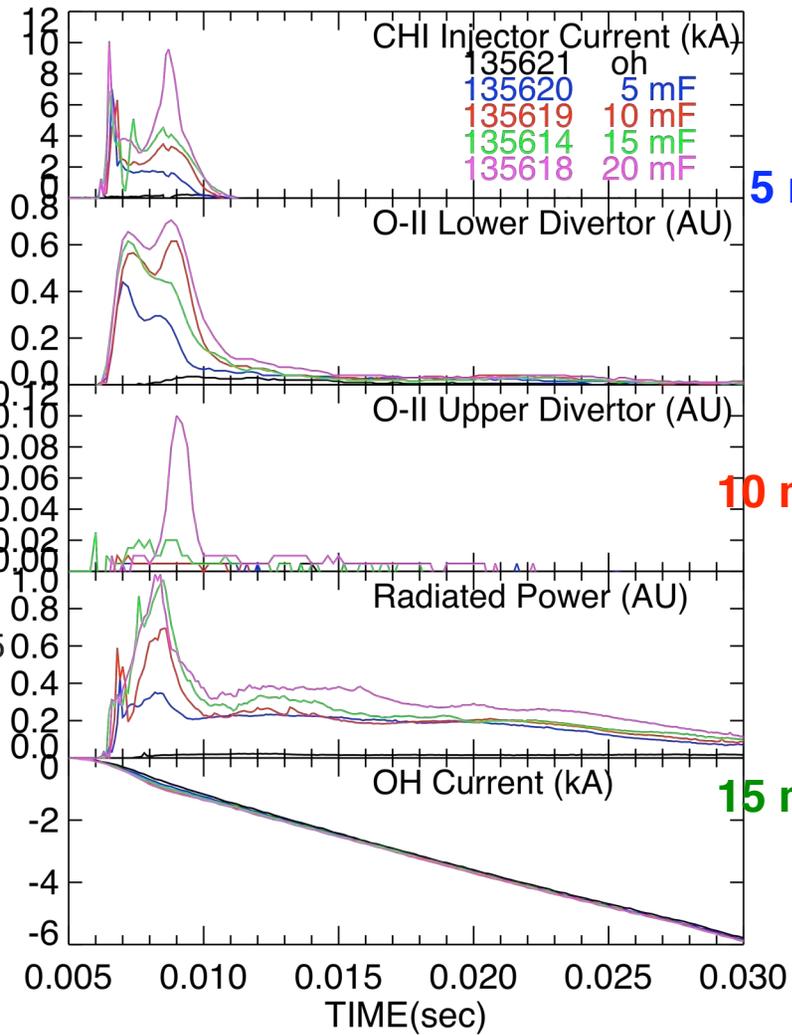
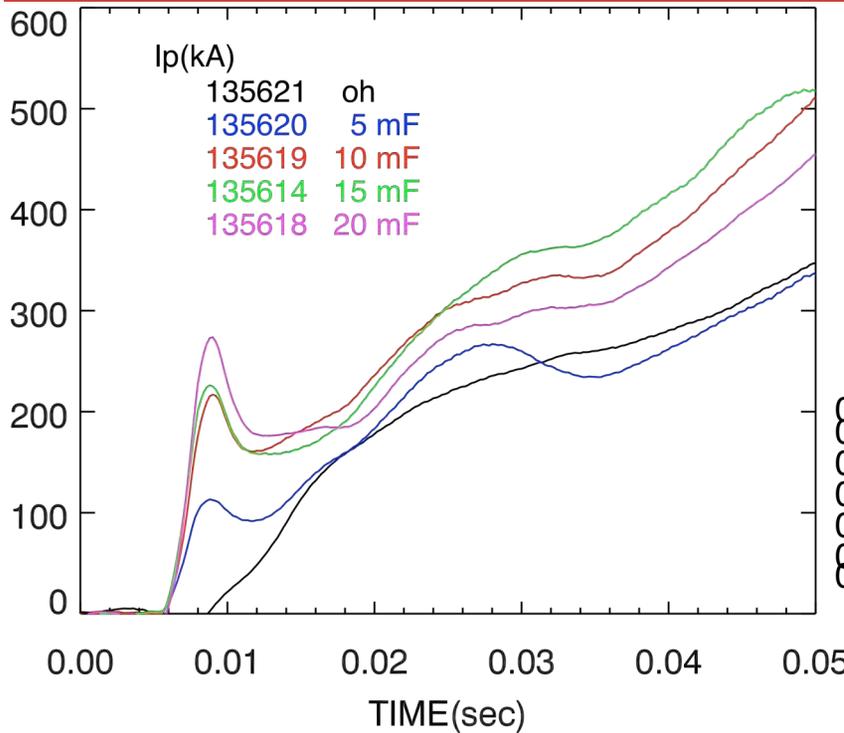


With Absorber Coils

Without

- Two CHI initiated discharges, one shown in blue with the absorber coils energized, the other in black has no current in the absorber coils
- The absorber clearly limit the vertical growth of the CHI plasma and prevent absorber arc
- Only the discharge without the arc couples to inductive ramp-up

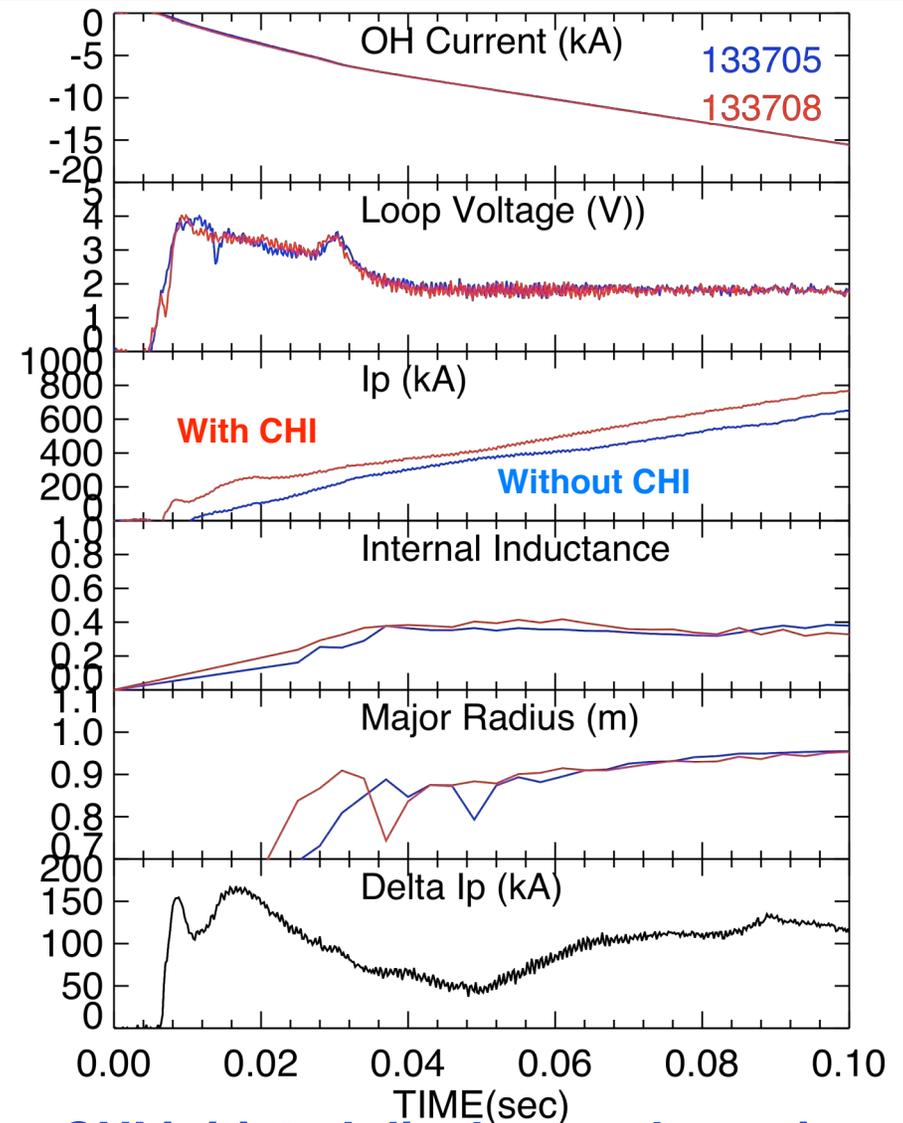
CHI increases I_p with increasing CHI energy until arc occurs



- Before conditioning and using absorber coils, CHI discharges using > 5 mF at 1.7 kV had absorber arcs
- $I_p \sim 200$ kA greater than ohmic only
- First successful coupling of OH with use of 20 mF (out of 50)

Comparison of well-controlled shots demonstrates a flux savings with CHI initiation

- I_p is 110 kA greater in the CHI initiated discharge
- The discharge in blue is a purely inductive discharge
 - Both had low levels of $O_{||}$ emission
 - The discharges had identical solenoid (OH) current programming
- The internal inductance, plasma radius and plasma shape (not shown) from EFIT analysis are essentially identical
- The density of the CHI initiated discharge was about 25% greater than the inductive only discharge



- *The CHI initiated discharge shown in red used 10 mF of capacitance at 1.65 kV*

Demonstrated progress in avoiding arcs during CHI, further improvements could raise CHI start-up current to near 0.5 MA

- **CHI discharges with low levels of low Z impurity radiation can be coupled to inductive ramp-up**
 - 400 ms duration CHI discharges condition lower divertor plates
 - Lithium evaporative coating (LITER) reduces low Z impurities
 - Buffer flux prevents plasma from reaching the absorber gap and causing an absorber arc
- **CHI start-up plasmas with current of up to 300 kA have been ramped inductively to produce a plasma current increase of 110 to 200 kA compared to inductive only**
 - Using about 1/3 of the available CHI capacitance

BACKUP SLIDES

CHI Scaling

- From helicity and energy conservation, for a Taylor minimum energy state $\lambda_{inj} \geq \lambda_{tok}$

$$-\lambda_{inj} = \mu_0 I_{inj} / \psi_{inj}; \psi_{inj} = \text{poloidal injector flux}$$

$$-\lambda_{tok} = \mu_0 I_p / \psi_{tok}; \psi_{tok} = \text{toroidal flux in vessel}$$

- $I_p \leq I_{inj} (\psi_{tok} / \psi_{inj})$
- For similar B_T NSTX has 10 times ψ_{tok} of HIT-II
- Bubble burst condition:

$$I_{inj} = 2 \psi_{inj}^2 / (\mu_0^2 d^2 I_{TF})$$

-For HIT-II, $\psi_{inj} = 8\text{mWb}$, $d = 8\text{ cm}$ is flux footprint width

-For NSTX, $\psi_{inj} = 10\text{mWb}$, $d = 16\text{ cm}$ is flux footprint width

- $I_{inj} \geq 15\text{ kA}$ for HIT-II, $I_{inj} \geq 2\text{ kA}$ for NSTX

- Sufficient energy to produce CHI discharge $W_{cap} > W_{plasma}; \frac{1}{2} CV^2 > \frac{1}{2} L_p I_p^2$
 - L_p plasma inductance $\sim 0.5\ \mu\text{H}$, and $C = 50\text{ mF}$ limits I_p to $\sim 500\text{ kA}$ for present NSTX system
- NSTX has achieved $I_p > 60 I_{inj}$; HIT-II has achieved $I_{inj} \sim 50\text{ kA}$

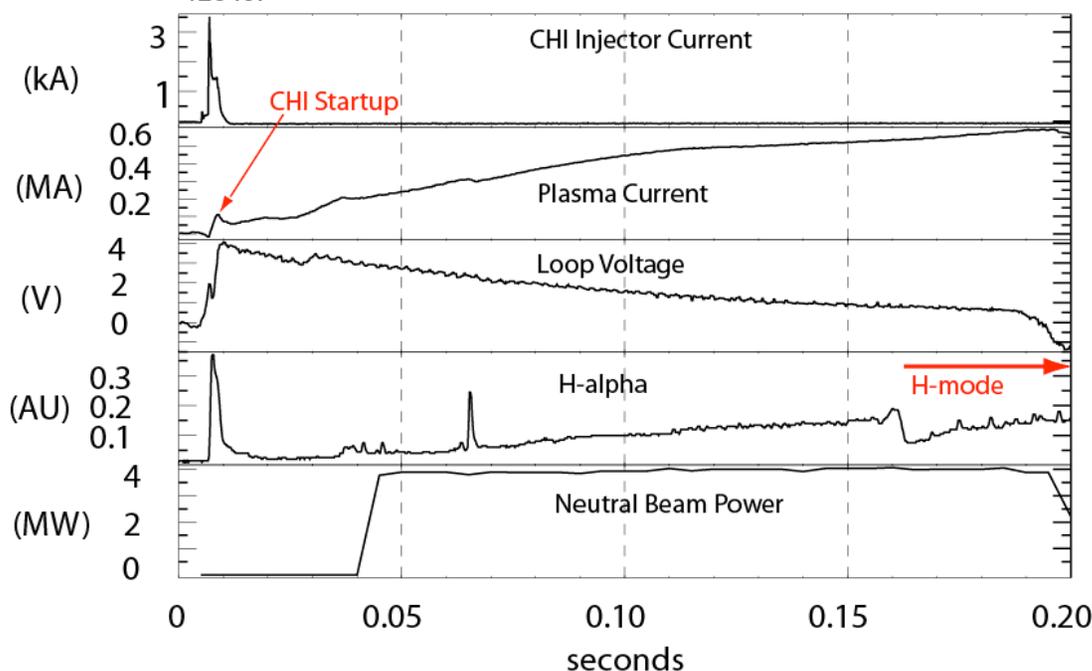
$\Rightarrow I_p$ over 2.5 MA is possible for CTF if $I_{inj} \sim 50\text{ kA}$

CHI started discharge couples to induction and transitions to an H-mode demonstrates compatibility with high-performance plasma operation

- Discharge is under full plasma equilibrium position control

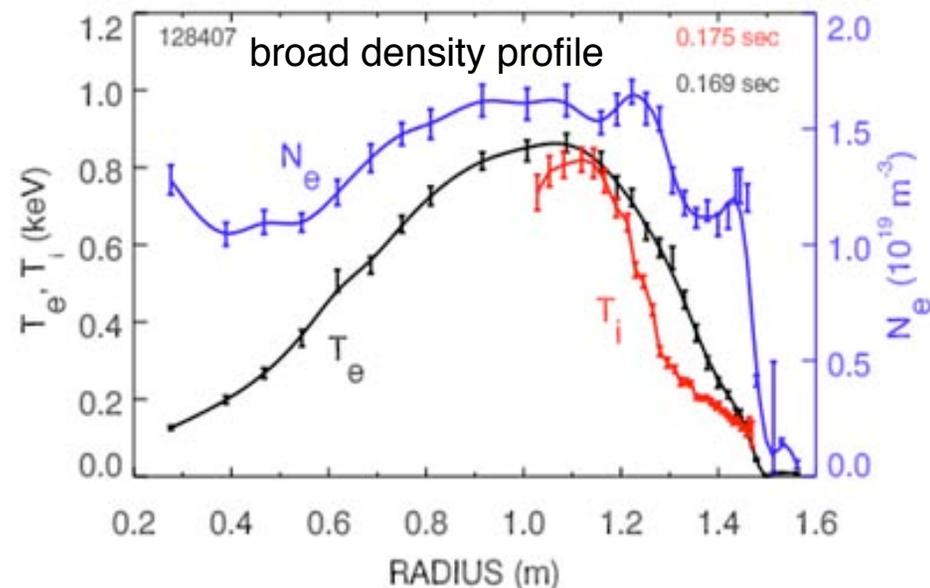
- Loop voltage is preprogrammed

128407



Te & Ne from Thomson

Ti from CHERS



Central Te reaches 800eV

Central Ti > 700eV

• PAC-23

- Projected plasma current for $CTF > 2.5$ MA $[I_p = I_{inj}(\psi_{Tor}/\psi_{Pol})]^*$
 - Based on 50 kA injected current (Injector current densities achieved on HIT-II)
 - Current multiplication of 50 (achieved in NSTX)
 - In HIT-II nearly all CHI produced closed flux current is retained in the subsequent inductive ramp

CHERS: R. Bell, Thomson: B. LeBlanc

*T.R. Jarboe, Fusion Technology, 15 (1989) 7